**Amendments to the Claims:**

This listing of claims will replace all prior versions, and listings, of claims in the application:

**Listing of Claims:**

1. (Currently Amended) A less-dust-generative piezoelectric/electrostrictive device comprising:

a thick ceramic substrate; and

a plurality of pillar shaped piezoelectric/electrostrictive elements which are formed integrally with the ceramic substrate and which extend upwardly from the ceramic substrate ~~in a matrix~~ to form at least a 2×2 matrix, each of said piezoelectric/electrostrictive elements comprising a piezoelectric/electrostrictive member and at least one pair of electrodes formed on side surfaces of the piezoelectric/electrostrictive member,

wherein the side surfaces of the piezoelectric/electrostrictive member on which the electrodes are formed are fired, but unprocessed faces.

Claims 2 and 3 (Cancelled)

4. (Previously Presented) The less-dust-generative matrix-type piezoelectric/electrostrictive device according to claim 1, wherein an aspect ratio of the piezoelectric/electrostrictive element having the pillar shape is in a range of about 20 to 400.

5. (Original) The less-dust-generative matrix-type piezoelectric/electrostrictive device according to claim 4, wherein a distance between at least one pair of electrodes formed on side surfaces of the piezoelectric/electrostrictive member constituting the piezoelectric/electrostrictive element is 300 µm or less in a transverse surface of the piezoelectric/electrostrictive element having the pillar shape.

6. (Original) The less-dust-generative matrix-type piezoelectric/electrostrictive device according to claim 5, wherein a ratio of a distance between one piezoelectric/electrostrictive element and the other piezoelectric/electrostrictive element disposed adjacent to the piezoelectric/electrostrictive element to a height of the one piezoelectric/electrostrictive element is in a range of about 1:20 to 1:400.

7. (Previously Presented) The less-dust-generative matrix-type piezoelectric/ electrostrictive device according to claim 1, wherein straightness of an axial line of the piezoelectric/electrostrictive element having the pillar shape is about 30 μm or less.

8. (Previously Presented) The less-dust-generative matrix-type piezoelectric/ electrostrictive device according to claim 1, further comprising: positional deviation inhibition means which holds accuracy of a position of the piezoelectric/electrostrictive element.

9. (Previously Presented) The less-dust-generative matrix-type piezoelectric/electrostrictive device according to claim 8, wherein the positional deviation inhibition means is a member disposed in at least a tip end of the piezoelectric/electrostrictive member constituting at least one of the piezoelectric/electrostrictive elements disposed adjacent to each other among the plurality of piezoelectric/electrostrictive elements set up on the ceramic substrate.

10. (Original) The less-dust-generative matrix-type piezoelectric/electrostrictive device according to claim 9, wherein the piezoelectric/electrostrictive element includes a stair-like member in a root of the piezoelectric/electrostrictive member.

Claims 11 and 12 (Cancelled)

13. (Previously Presented) The less-dust-generative cell-driving type piezoelectric/electrostrictive device according to claim 24, wherein an aspect ratio of the piezoelectric/electrostrictive element having the thin wall shape is in a range of about 2 to 40.

14. (Previously Presented) The less-dust-generative cell-driving type piezoelectric/electrostrictive device according to claim 24, further comprising:

a plurality of cells each of which is formed independently of the adjacent cell,

wherein a ratio of a distance between one cell and another cell disposed adjacent to said one cell to a height of the piezoelectric/electrostrictive element is in a range of about 1:2 to 1:100.

Claims 15 and 16 (Cancelled)

17. (Original) A guide-attached matrix type piezoelectric/electrostrictive device comprising:

a thick ceramic substrate;

a plurality of piezoelectric/electrostrictive elements which are set up in a matrix form on the ceramic substrate and each of which includes a piezoelectric/electrostrictive member and at least one pair of electrodes formed on side surfaces of the piezoelectric/electrostrictive member to have a pillar shape and which are integrally formed with the ceramic substrate; and

positional deviation inhibition means which holds accuracy of a position of the piezoelectric/electrostrictive element.

18. (Original) The guide-attached matrix-type piezoelectric/electrostrictive device according to claim 17, wherein the positional deviation inhibition means is a convex member disposed in at least a tip end of the piezoelectric/electrostrictive member constituting at least one of the piezoelectric/electrostrictive elements disposed adjacent

to each other among the plurality of piezoelectric/electrostrictive elements set up on the ceramic substrate.

19. (Original) The guide-attached matrix-type piezoelectric/electrostrictive device according to claim 17, wherein the piezoelectric/electrostrictive element includes a stair-like member in a root of the piezoelectric/electrostrictive member.

Claims 20-23 (Cancelled)

24. (Previously Presented) A less-dust-generative piezoelectric/electrostrictive device comprising:

a ceramic substrate;

two or more thin walled piezoelectric/electrostrictive elements which are formed integrally with the ceramic substrate and which extend upwardly from the ceramic substrate, each piezoelectric/electrostrictive element comprising a piezoelectric/electrostrictive member and at least one pair of electrodes formed on side surfaces of the piezoelectric/electrostrictive member; and

at least one cell including the ceramic substrate, one piezoelectric/electrostrictive element, another piezoelectric/electrostrictive element disposed adjacent to the one piezoelectric/electrostrictive element, and a lid section connecting the one piezoelectric/electrostrictive element to the other piezoelectric/electrostrictive element,

wherein the side surfaces of the piezoelectric/electrostrictive device on which the electrodes are formed are fired, but unprocessed faces.

25. (Previously Presented) The less-dust-generative piezoelectric/electrostrictive device according to claim 1, wherein the side surfaces of the piezoelectric/electrostrictive device on which the electrodes are formed have a homogenous surface.

26. (Previously Presented) The less-dust-generative piezoelectric/electrostrictive device according to claim 24, wherein the side surfaces of the piezoelectric/electrostrictive device on which the electrodes are formed have a homogenous surface.

27. (New) A less-dust-generative piezoelectric/electrostrictive device comprising:

a thick ceramic substrate; and

a plurality of pillar shaped piezoelectric/electrostrictive elements which are formed integrally with the ceramic substrate and which extend upwardly from the ceramic substrate to form at least a 2×2 matrix, each of said piezoelectric/electrostrictive elements comprising a piezoelectric/electrostrictive member and at least one pair of electrodes formed on side surfaces of the piezoelectric/electrostrictive member,

wherein the side surfaces of the piezoelectric/electrostrictive member on which the electrodes are formed are fired, but unprocessed faces, and the piezoelectric/electrostrictive elements are wired via a through hole or a via hole formed in the ceramic substrate.

28. (New) A less-dust-generative piezoelectric/electrostrictive device comprising:

a thick ceramic substrate; and

a plurality of pillar shaped piezoelectric/electrostrictive elements which are formed integrally with the ceramic substrate and which extend upwardly from the ceramic substrate to form at least a 2×2 matrix, each of said piezoelectric/electrostrictive elements comprising two or more layers of piezoelectric/electrostrictive members and electrodes formed on opposite outer surfaces of the two or more layers of piezoelectric/electrostrictive members and between two or more layers of piezoelectric/electrostrictive members,

wherein the surfaces of the piezoelectric/electrostrictive members on which the electrodes are formed are fired, but unprocessed faces.

29. (New) A less-dust-generative piezoelectric/electrostrictive device comprising:

a ceramic substrate;

two or more thin walled piezoelectric/electrostrictive elements which are formed integrally with the ceramic substrate and which extend upwardly from the ceramic substrate, each piezoelectric/electrostrictive element comprising two or more layers of piezoelectric/electrostrictive members and electrodes formed on opposite outer surfaces of the two or more layers of piezoelectric/electrostrictive members and between the two or more layers of piezoelectric/electrostrictive members; and

at least one cell including the ceramic substrate, one piezoelectric/electrostrictive element, another piezoelectric/electrostrictive element disposed adjacent to the one piezoelectric/electrostrictive element, and a lid section connecting the one piezoelectric/electrostrictive element to the other piezoelectric/electrostrictive element,

wherein the surfaces of the piezoelectric/electrostrictive device on which the electrodes are formed are fired, but unprocessed faces.